



Dare più valore alla misura: integrazione tra metrologia e l'ecosistema informativo aziendale.

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Global Trends

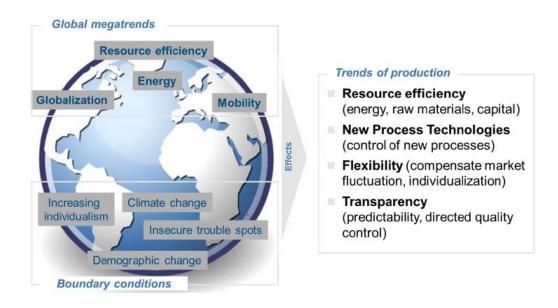


Figure 1. Global trends and trends in manufacturing technology (image source: WZL, RWTH Aachen).

Challenges and trends in manufacturing metrology – VDI/VDE Roadmap





Cyber Physical Production System (CPPS)

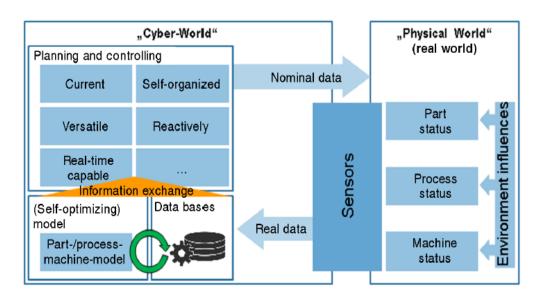


Figure 2. Concept of a cyber-physical production system.

Challenges and trends in manufacturing measurement technology – the "Industrie 4.0" concept





Manufacturing Metrology

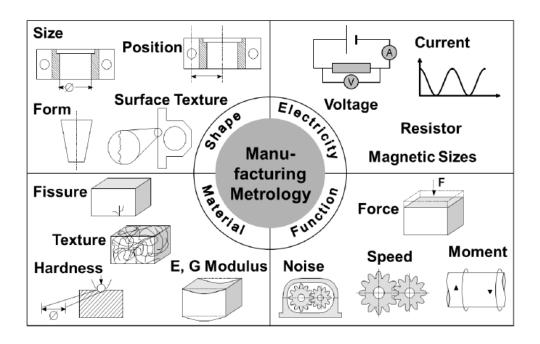


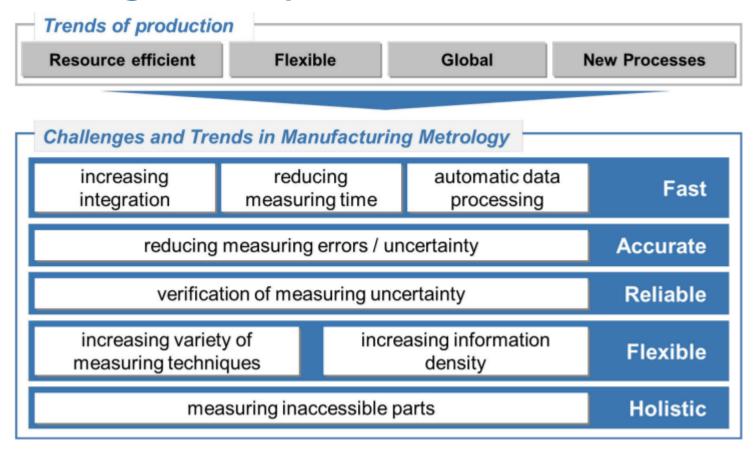
Figure 2. Fields of application for manufacturing metrology (derived from Pfeifer and Schmitt, 2010).

Looking at the future of manufacturing metrology: roadmap document of the German VDI/VDE Society for Measurement and Automatic Control





Metrologic Requirements and Trends

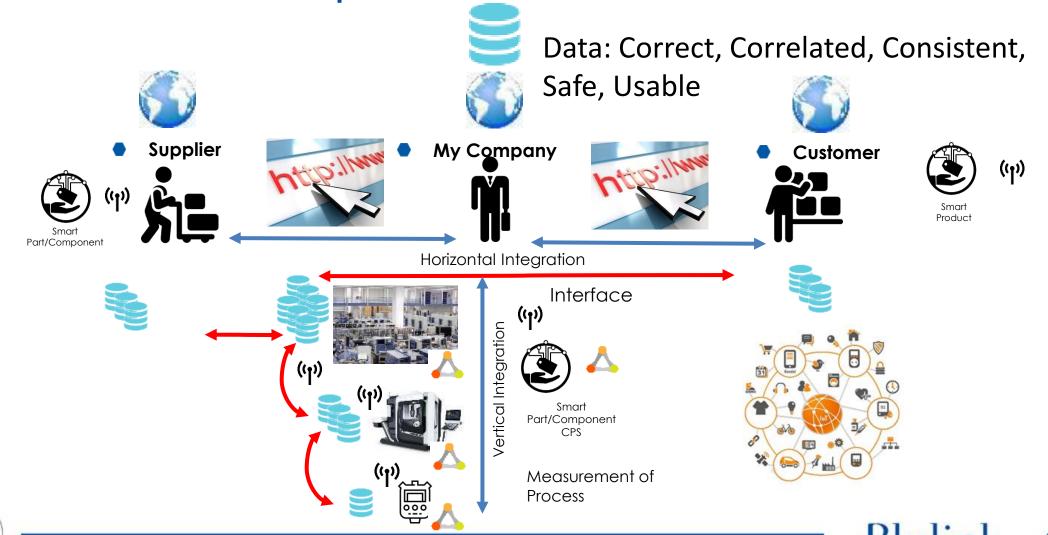


Requirements and trends from the VDI 2020 Manufacturing Metrology Roadmap (updated in 2015)





Trend: Competences, Complexity, Data, Technology – Speed and Growth



QMIS as a Gateway

- Machine Learning (ML) BIG DATA
- Enterprise Information System (ERP, MES, ...)
- **Cloud Platform**



Gateway















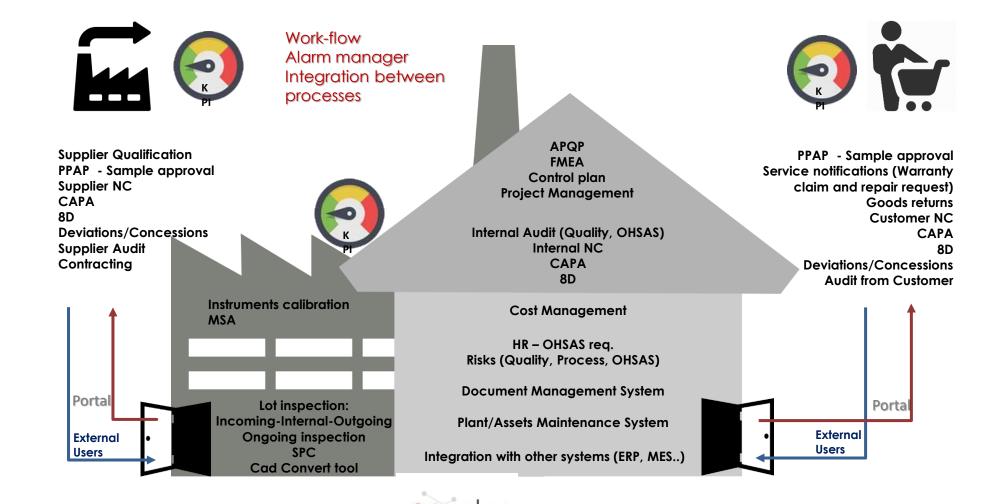








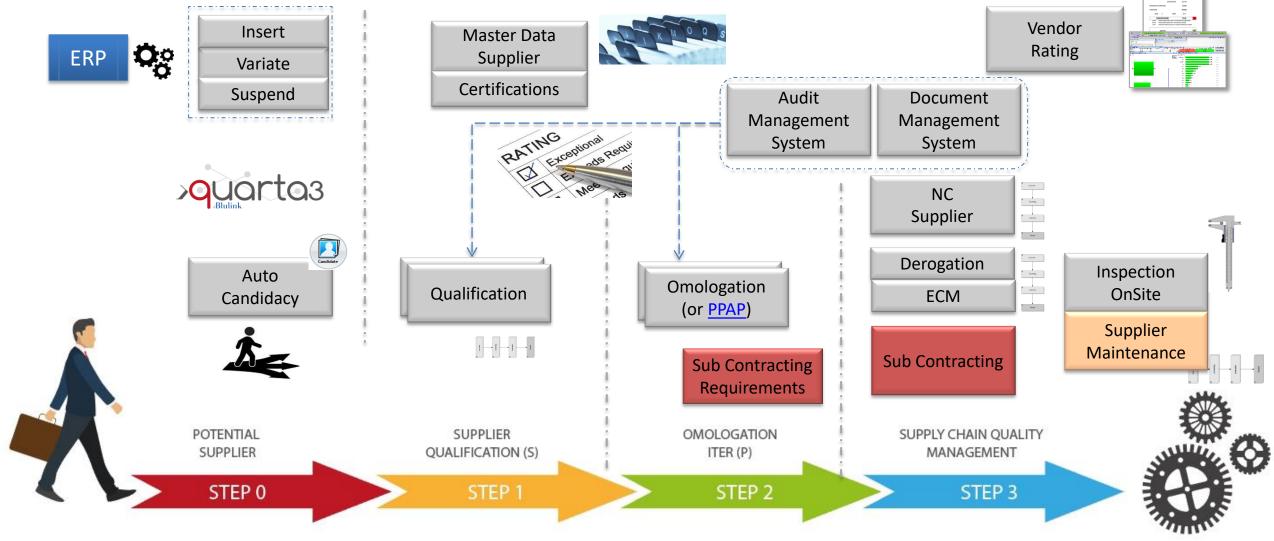
QMIS – Functions







QMIS – Supplier Portal







The Flow



Part Nr. PART001

INCOMING

Part Nr - Supplier

PRODUCTION

Part Nr - Operation

SPECIAL ACTIONS

Part Nr - Operation

- · Hourly controls
- Change Shift controls
- Change setup controls
- Change tools controls

Outgoing



Incoming Inspection Module



Quartas Internal Inspection Module

Ougarto On going Inspection Module/SPC



Incoming Inspection Cycle





Incoming Inspection Control process



MARPOSS

Internal Inspection Cycle



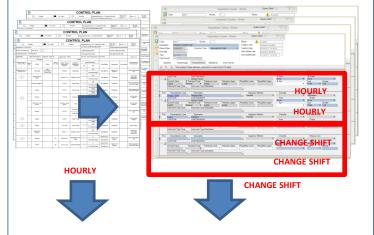


Internal Inspection Control process



- Characteristics Values
- Serial Numbers

On going Inspection Cycle / SPC



On going Inspection Control process



Outgoing Inspection Cycle

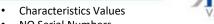




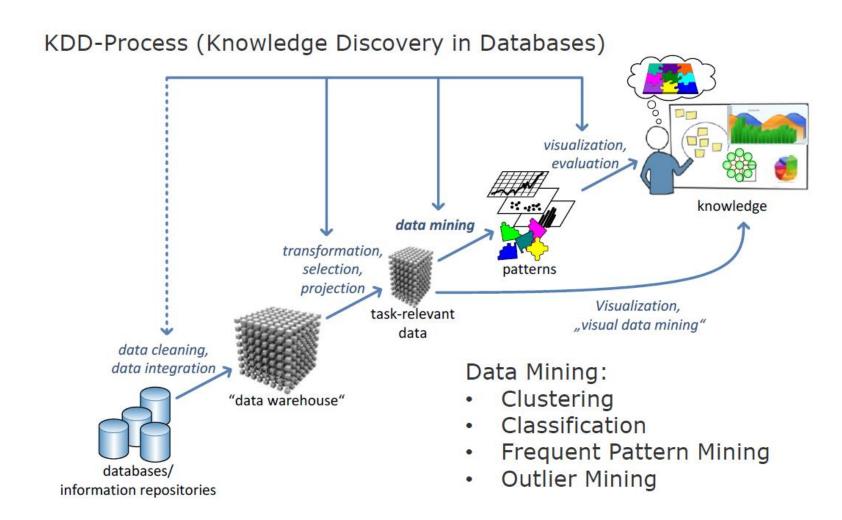
OutgoingControl process



- NO Serial Numbers









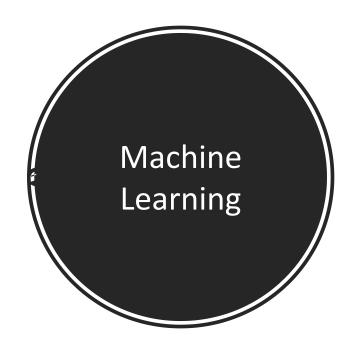


Difference - Unsupervised / Supervised learning? <u>Clustering: Unsupervised learning</u>

- The class labels of training data are unknown
- Given a set of measurements, observations etc. with the aim of establishing the existence of classes or clusters in the data.
 - Classes (=Clusters are unknown)
 - You don't know what you are looking for

Classification: Supervised learning

- Supervision: The training data (observations, measurements etc) are accompanied by labels the class of the observation
 - Classes are known in advance
 - you know what you are looking for
- New data is classified based on the information extracted from the training set







Blulink becomes part of VALUE BEYOND COMPLIANCE



Group









INTEGRATION QUARTA3 & MARPOSS MEASURING INSTRUMENTS



NEW SKILLS



Measurement and **EDGE Technology** for Blulink









Quality & Safety Platform

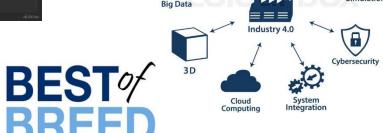


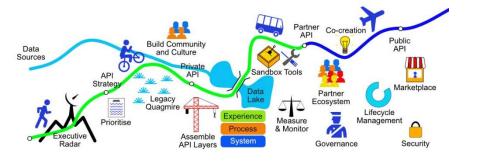
















Thanks for your attention



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